



Inventor: John T. Moore

Title: Method of Forming Oxide Regions Over Semiconductor Substrates

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

References – See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. No admission is made regarding whether any of the submitted references is prior art. Copies of the references are attached.

Respectfully submitted,

Dated:

May 12, 2004

Attorney:

Jennifer J. Taylor
Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1384		SERIAL NO. 09/602.395	
<div style="display: flex; align-items: center; justify-content: center;"> <div style="margin-left: 10px;"> LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) </div> </div>				APPLICANT John T. Moore			
				FILING DATE June 22, 2000		GROUP 2813	
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA	6,100,163	08-2000	Jang et al.				
AB	6,399,520 B1	06-2002	Kawakami et al.				
AC							
AD							
AE							
AF							
AG							
AH							
AI							
AJ							
AK							
AL							
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
AM							
AN							
AO							
AP							
AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR						
	AS						
	AT						
EXAMINER				DATE CONSIDERED			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							